

**CERTIFICATE OF MAILING BY FIRST CLASS MAIL (37 CFR 1.8)**

Applicant(s): **GEUN-YOUNG YEOM, ET AL.**

Docket No.

**HNE-0001**

Serial No.

**10/010,548**

Filing Date

**11/08/2001**

**MAR 10 2004**

Examiner

**Tran, Binh X.**

Group Art Unit

**1765**

Invention: **METHOD OF ETCHING SEMICONDUCTOR DEVICE USING NEUTRAL BEAM AND APPARATUS FOR ETCHING THE SAME**

I hereby certify that this **Response to Office Action; Limited Recognition under 37 CFR Section 10.9(b)**

*(Identify type of correspondence)*

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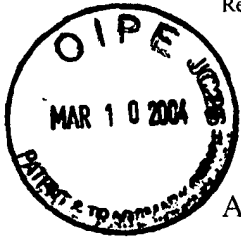
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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANT:	Geun-Young Yeom, et al.	) Examiner:
		) Tran, Binh X.
SERIAL NO.:	10/010,548	)
		)
FILED:	November 8, 2001	) Art Unit:
		) 1765
FOR:	METHOD OF ETCHING	)
	SEMICONDUCTOR DEVICE USING	)
	NEUTRAL BEAM AND APPARATUS	)
	FOR ETCHING THE SAME	)

Mail Stop: AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Dear Sir:

Applicants respectfully request entry of the following amendment and remarks contained herein in response to the Office Action mailed January 7, 2004. Applicants respectfully submit that the amendment and remarks contained herein place the instant application in condition for allowance.